

(19) World Intellectual Property  
Organization  
International Bureau



(43) International Publication Date  
26 May 2005 (26.05.2005)

PCT

(10) International Publication Number  
**WO 2005/047177 A1**

(51) International Patent Classification<sup>7</sup>: **B82B 3/00**,  
C23C 16/04, H01J 37/317

(21) International Application Number:  
PCT/IB2004/003696

(22) International Filing Date:  
9 November 2004 (09.11.2004)

(25) Filing Language: English

(26) Publication Language: English

(30) Priority Data:  
03405806.5 12 November 2003 (12.11.2003) EP

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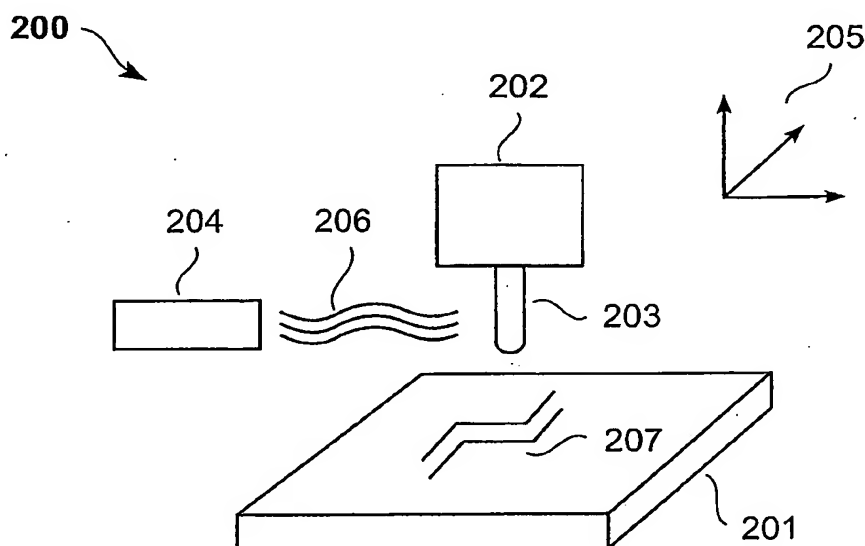
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(81) Designated States (unless otherwise indicated, for every  
kind of national protection available): AE, AG, AL, AM,  
AT, AU, AZ, BA, BB, BG, BR, BW, BY, BZ, CA, CH, CN,  
CO, CR, CU, CZ, DE, DK, DM, DZ, EC, EE, EG, ES, FI,  
GB, GD, GE, GH, GM, HR, HU, ID, IL, IN, IS, JP, KE,  
KG, KP, KR, KZ, LC, LK, LR, LS, LT, LU, LV, MA, MD,  
MG, MK, MN, MW, MX, MZ, NA, NI, NO, NZ, OM, PG,  
PH, PL, PT, RO, RU, SC, SD, SE, SG, SK, SL, SY, TJ, TM,  
TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, YU, ZA, ZM,  
ZW.

(84) Designated States (unless otherwise indicated, for every  
kind of regional protection available): ARIPO (BW, GH,

[Continued on next page]

(54) Title: **DEVICE AND METHOD FOR PATTERNING STRUCTURES ON A SUBSTRATE**



(57) Abstract: A device for patterning structures on a substrate comprising an imaging device having a scanning tip a light emitting device, and a space around the scanning tip, which space comprises a vapour of a material which is suitable for Chemical Vapour Deposition onto the substrate when decomposed, wherein the light emitting device is adapted to emit a light beam, which light beam has an intensity that is not capable to decompose the vapour, onto the scanning tip in such a way that an electromagnetic field induced by the light beam near the scanning tip is high enough to decompose the vapour.

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GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW), Eurasian (AM, AZ, BY, KG, KZ, MD, RU, TJ, TM), European (AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IS, IT, LU, MC, NL, PL, PT, RO, SE, SI, SK, TR), OAPI (BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG).

**Published:**

— with international search report

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